

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Grimbergen et al.	Group Art Unit: 1763
Application No: 09/595,778	Examiner: Allan W. Olsen
Confirmation No: 6490	Attorney Docket No:
Filed: June 16, 2000	2077 USA D01/ETCH/SILICON/DAO
Title: APPARATUS AND METHOD FOR MONITORING PROCESSING OF A SUBSTRATE	July 23, 2008 San Francisco, California

SUBMISSION OF DECLARATION PURSUANT TO 37 C.F.R. § 1.131

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Examiner Olsen:

This communication is in supplement to the Amendment and RCE filed June 19, 2008. Attached please find a Declaration from Michael Grimbergen and Shaoher Pan that antedates the present invention over Chiu et al.

Should the Examiner have any questions regarding the attached Declaration and Exhibits, the Examiner is requested to telephone the undersigned representative at: (415) 538-1555.

Respectfully submitted,

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